



Ifu 2882

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Dated: June 7, 2007

Signature: \_\_\_\_\_

(Andrew T. Zidel)

Docket No.: XENOCs 3.3-002  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Hoghoj et al.

Application No.: 10/518,284 ✓

Group Art Unit: 2882

Filed: September 2, 2005

Examiner: C. C. G. Kao

For: AN OPTICAL DEVICE FOR X-RAY  
APPLICATIONS

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Dear Sir:

It is respectfully requested that the references listed on the enclosed form be made of record and considered with respect to the above-referenced U.S. patent application. A copy of each reference which is not a U.S. patent or patent application is enclosed. Submission of the present Information Disclosure Statement should not be taken as an admission that the cited references are legally available prior art or that the same are pertinent or material.

In the event that any fee is due in connection with the present Information Disclosure Statement, the Commissioner is hereby authorized to charge the same to our Deposit Account No. 12-1095.

Dated: June 7, 2007

Respectfully submitted,

By \_\_\_\_\_

Andrew T. Zidel

Registration No.: 45,256

LERNER, DAVID, LITTENBERG,  
KRUMHOLZ & MENTLIK, LLP

600 South Avenue West  
Westfield, New Jersey 07090  
(908) 654-5000

Attorney for Applicant(s)



Used in Lieu of PTO/SB/08A/B  
(Based on PTO 04-07 version)

Substitute for form 1449/PTO  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use as many sheets as necessary)				<b>Complete if Known</b>	
				Application Number	10/518,284-Conf. #3519
				Filing Date	September 2, 2005
				First Named Inventor	Peter Hoghoj
				Art Unit	2882
				Examiner Name	C. C. G. Kao
Sheet	1	of	2	Attorney Docket Number	XENOCs 3.3-002

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
	AA*	US-5,999,262-A	12-07-1999	Dobschal et al.	
	AB*	US-6,317,483-B1	11-13-2001	Chen	
	AC*	US-5,799,056-A	08-25-1998	Gutman	
	AD*	US-6,278,764	08-21-2001	Barbee, Jr. et al.	
	AE*	US-5,619,548	04-08-1997	Koppel	
	AF*	US-6,041,099-A	03-21-2000	Gutman et al.	
	AG*	US-4,562,583-A	12-31-1985	Hoover et al.	
	AH*	US-5,127,028-A	06-30-1992	Wittry	
	AI*	US-20040096034-A1	05-20-2004	Michaelsen et al.	
	AJ*	US-5,142,561	08-25-1992	Doumas	
	AK*	US-6,285,506-B1	09-04-2001	Chen	
	AL*	US-6,226,349	05-01-2001	Schuster et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T <sup>6</sup>
		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)				
	BA	EP-0115892	08-15-1984	Philips Nv		✓
	BB	WO-02/103710-A2	12-27-2002	X-Ray Optical Systems, Inc.		✓
	BC	GB-2217036-A	10-18-1989	Rosser		✓
	BD	WO-108162	02-01-2001	Univ California		✓

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. \* CITE NO.: Those application(s) which are marked with an single asterisk (\*) next to the Cite No. are not supplied (under 37 CFR 1.98(a)(2)(iii)) because that application was filed after June 30, 2003 or is available in the IFW. <sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. <sup>3</sup> Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. <sup>6</sup> Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
	CA	NAUDON et al., "New Apparatus for Grazing Reflectometry in the Angle-Resolved Dispersive Mode", J. Appl. Cryst, Vol. 22, Part 5, pp. 460-464, October 1, 1989.	
	CB	M.P. Ulmer, Production and performance of multilayer coated conic sections, Jul 2001, SPIE, Vol. 4496, page 127-133.	
	CC	M.P. Ulmer, The Fabrication of Wolter I multilayer coated optics via electroforming: an update, Jul 1999, SPIE, Vol. 3773, page 113-121.	
	CD	M. Schuster et al., Laterally Graded Multilayer Optics for X-ray Analysis, SPIE, Vol. 3767, Jul 1999, Page 183-198.	
	CE	Romaine et al., Multilayer Optics for Hard X-ray Astronomy, SPIE, Vol. 4138, Nov. 2000, page 120-125.	
	CF	HEADRICK et al., "Mutlilayer Optics for a Wiggler Beamline (invited), March 2002, Review of Scientific Instruments, Vol. 43, No. 3, p. 1476-1479.	
	CG	G.E. ICE, "Microbeam Forming Methods for Synchrotron Radiation,"© 1997	

Examiner Signature		Date Considered	
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Sheet	2	of	2	Attorney Docket Number	XENOCs 3.3-002

	CH	OVONYX; Design News; "Focusing ring: first step toward scanning X-ray microscope," 13 pages	
	CI	Research & Development, November 1988 by B. Volbert "New X-ray Spectrometer Technology Improves Both Speed and Accuracy," 8 pages	
	CJ	MORAWE CH ET AL., entitled "Production of x-ray multilayer coatings by plasma sputtering" (VIDE; VIDE: SCIENCE, TECHNIQUE ET APPLICATIONS 1999 SOC FRANCAISE DU VIDE, FRANCE, vol. 4 (4), no. 294, 1999, pages 467-472)	
	CK	PING LEE, entitled: "Uniform and graded multilayers as X-ray optical elements" (APPLIED OPTICS USA, vol. 22, no. 8, 15 April 1983 (1983-04-15), pages 1241-1246)	
	CL	KLEINEBERG et al., "Bufferlayer and Caplayer Engineering of Mo/Si EUVL Multilayer Mirrors", Soft X-Ray and EUV Imaging Systems II, Daniel A. Tichenor, James A. Folta, Editors, Proceedings of SPIE, Vol. 4506 (2001), pp. 113-120.	
	CM	NIGGEMEIER et al., "X-ray Reflectometer for the Diagnostics of Thin Films During Growth", Journal of Applied Crystallography (1997), 30, 905-908.	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.

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